

■ Requirement to Next Generation Cellular Phone

Expansion of usable frequency band

Improvement of frequency characteristics of high frequency devices (Amplifier, Filter, etc.)

Weight saving, Low price

CSP (Chip Size Package)



ULVAC Solutions

- Vacuum Equipment
- Analytical
- Material
- Service



Sputtering System

MLX-3000N

for high frequency devices



ULVAC, Inc.

- Stress and stoichiometry controllable for deposition film.
- applicable to resist coated wafers with substrate cooling system.

Dry Etching System

APIOS NE-7800

for high frequency devices



ULVAC, Inc.

- High density plasma source loaded.
- For high rate and vertical etching of GaAs.

Vacuum Evaporation System

EBX-2000

for high frequency devices



ULVAC, Inc.

- Substrate holder adopted for a typical substrate.
- Excellent film thickness uniformity with precise deposition rate control.